2814

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re t	the Application of)
Kazuo MAEDA) Examiner: Quach
Serial No.: 09/519,599)) Art Unit: 2814
Filed: March 6, 2000)
For:	METHOD AND APPARATUS FOR FORMING AN INTERLAYER INSULATING FILM AND SEMICONDUCTOR DEVICE)))

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RESPONSE TO OFFICE ACTION OF SEPTEMBER 10, 2001

Assistant Commissioner for Patents Washington, D.C. 20231

OCT 0 1 2001

Sir:

Applicants, by their undersigned attorney, hereby elect Group I (claims 1-27) for prosecution. However, insofar as the examiner separates I and III, the requirement is traversed. In justifying the division of claims 33-39 from claims 1-27 the examiner writes:

In the instant case the product can be made by another process wherein the annealing precedes the film deposition as delineated above.

The examiner's statement cannot possibly be correct because the annealing step reads "annealing said film." How can the film be annealed before it is formed? What the examiner suggests is a rationale for separation of Groups I and III is an impossibility.

Accordingly, it is respectfully requested that the examiner modify the restriction requirement to the extent that it would separate the claims of Groups I and Π I.

Respectfully submitted;

George A

Reg. No. 25,814

Dated: October 1, 2001

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